



#7

Sheet 1 of 5

FORM PTO-1449

INFORMATION DISCLOSURE CITATION
IN AN APPLICATION

(Use several sheets if necessary)

Docket Number (Optional)

823.0052USQ

Application Number

09/739,940

Applicant

Fonash et al.

Filing Date

December 19, 2000

Group Art Unit

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U. S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)

MOT ↓	Uhlir, Jr. "Electrolytic shaping of Geranium and Silicon." Bell Syst. Tech. J. 35, 333-347 (1956).
↓	Watanabe et al. "Application of a thick anode film to semiconductor devices." Review of Electrical Communication Laboratories, Vol. 19, No. 7-8, July-August 1971.
MCS	Anderson et al. "Porous Polycrystalline Silicon: A new material for MEMS." J. of Microelectromechanical Systems, Vol. 3, No. 1, March 1994.

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DATE CONSIDERED

4/5/02

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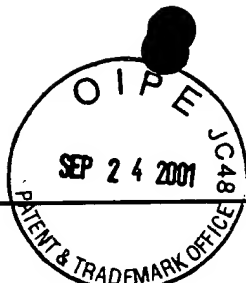
MCT ↓	Messier et al. "Black a-Si solar selective absorber surfaces." J. Appl. Phys. 51(3), March 1980.
MCT ↓	Canham. "Silicon quantum wire array fabrication by electrochemical and chemical dissolution of wafers." Appl. Phys. Lett. 57(10), 3 September 1990.
MCT ↓	Schechter. "Gas sensing properties of porous silicon." Anal. Chem. 1995, 67, 3727-3732.

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MCS	Wei et al. "Desorption-ionization mass spectrometry on porous silicon." NATURE, Vol. 399, 243-246, 20 May 1999.
↓	Canham et al. "Calcium phosphate nucleation on porous silicon: factors influencing kinetics in acellular simulated body fluids." Thin Solid Films 297 (1997) 304-307.
MCS	Steiner et al. "Micromachining applications of porous silicon." Thin Solid Films 255 (1995) 52-58.

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U. S. PATENT DOCUMENTS

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FOREIGN PATENT DOCUMENTS

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						YES	NO

OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)

MCF ↓ MCF	Fonash et al. " Nanostructured silicon for Bio-medical applications." Nanofabrication Facility, 189 MRI Building, The Pennsylvania State University, University Park, PA 16802.
	Hayes et al. "Desorption-ionization mass spectrometry using deposited nanostructured silicon films." Anal. Chem. 2001, 73, 1292-1295.
	Shen et al. "Porous silicon as a versatile platform for laser desorption/ionization mass spectrometry." Anal. Chem. 2001, 73, 612-619.

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	823.0052USQ	09/17/99 940
	Applicant	
	Fonash et al.	
Filing Date	Group Art Unit	
December 19, 2000	1771	

U. S. PATENT DOCUMENTS

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OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)

MCF	Kruse et al. "Experimental factors controlling analyte ion generation in laser desorption/ionization mass spectrometry on porous silicon." Analytical Chemistry. Published on the Web.

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